

PATENT

Atty. Docket No.: 006915 USA P02/FEP/P3I/PJT
RW Ref. No.: APM/001-02-CP1-2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re:)
Kenneth Collins, et al.)
)
Entitled: PLASMA IMMERSION ION) Group Art Unit: 2893
IMPLANTATION APPARATUS USING A)
PLASMA SOURCE HAVING LOW)
DISSOCIATION AND LOW MINIMUM PLASMA)
VOLTAGE)
) Examiner: Jack S. Chen
Application Serial No.: 10/646,533)
)
Application Filing Date:)
08/22/2003)

LETTER TO THE EXAMINER


Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached please find a copy of an official action issued in a related application already of record in the present application (official action dated 11/25/2009 in Appln. Serial No. 11/600,680).

Respectfully submitted,

Dated 12/04/09


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